

SHEET 1 OF 1

| INFORMATION DISCLOSURE CITATION IN AN APPLICATION. | | | | ATTY. DOCKET NO. 49959-220 | | SERIAL NO. 09/986,137 | |
|---|-------------|---|--------------------------------|--|---|--------------------------|----|
| (PTO-1449) | | | | APPLICANT Gilad ALMOGY, et al. | | | |
| | | | | FILING DATE November 07, 2001 | | GROUP 2881 | |
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| | | | | APPLICANT Gilad ALMOGY, et al. | | | |
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